

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of: Sang Kuk CHOI
Serial No.: New Application Group Art Unit: Not Yet Assigned
Filed: July 14, 2003 Examiner: Not Yet Assigned
Title: DEFLECTOR OF A MICRO-COLUMN ELECTRON BEAM APPARATUS AND
METHOD FOR FABRICATING THE SAME

INFORMATION DISCLOSURE STATEMENT

Honorable Commissioner for Patents
PO Box 1450,
Alexandria, VA 22313

July 14, 2003

Sir:

As a means of complying with the duty of disclosure under 37 CFR §1.56, and in accordance with 37 CFR §§1.97 and 1.98, Applicant(s), through the undersigned attorney, submits this Information Disclosure Statement. The patents, publications or other information submitted herewith are listed on the attached Form PTO-1449 and copies are attached.

In accordance with 37 CFR §1.97(b)(1) or (2), this Information Disclosure Statement is being filed either within three months of the filing date of the above-identified application, or within three months of the date of entry into the national stage of the above-identified application as set forth in 37 CFR §1.491. Accordingly, no fee is required.

Respectfully submitted,

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LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT

ATTY. DOCKET NO.: P69018US0 GROUP ART UNIT: Not Yet Assigned
SERIAL NO.: Not Yet Assigned FILING DATE: July 14, 2003
APPLICANT(S): Sang Kuk CHOI, et al. TODAY'S DATE: July 14, 2003

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	INT'L CLASS	SUB- CLASS	FILING DATE (If Appropriate)
AA						
AB						

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB- CLASS	TRANSLATION (YES) (NO)
AC	2001-51486	06/25/01	KOREA (ROK)	H01J	29/48	X
AD						
AE						

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

AF L.P. Muray, et al.; "Advances in arrayed microcolumn lithography";
J. Vac. Sci. Technol. B 18(6); Nov/Dec 2000; American Vacuum
Society; pp. 3099-3103.

AG _____

EXAMINER

DATE CONSIDERED

* EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant(s).